

FIG. 1A

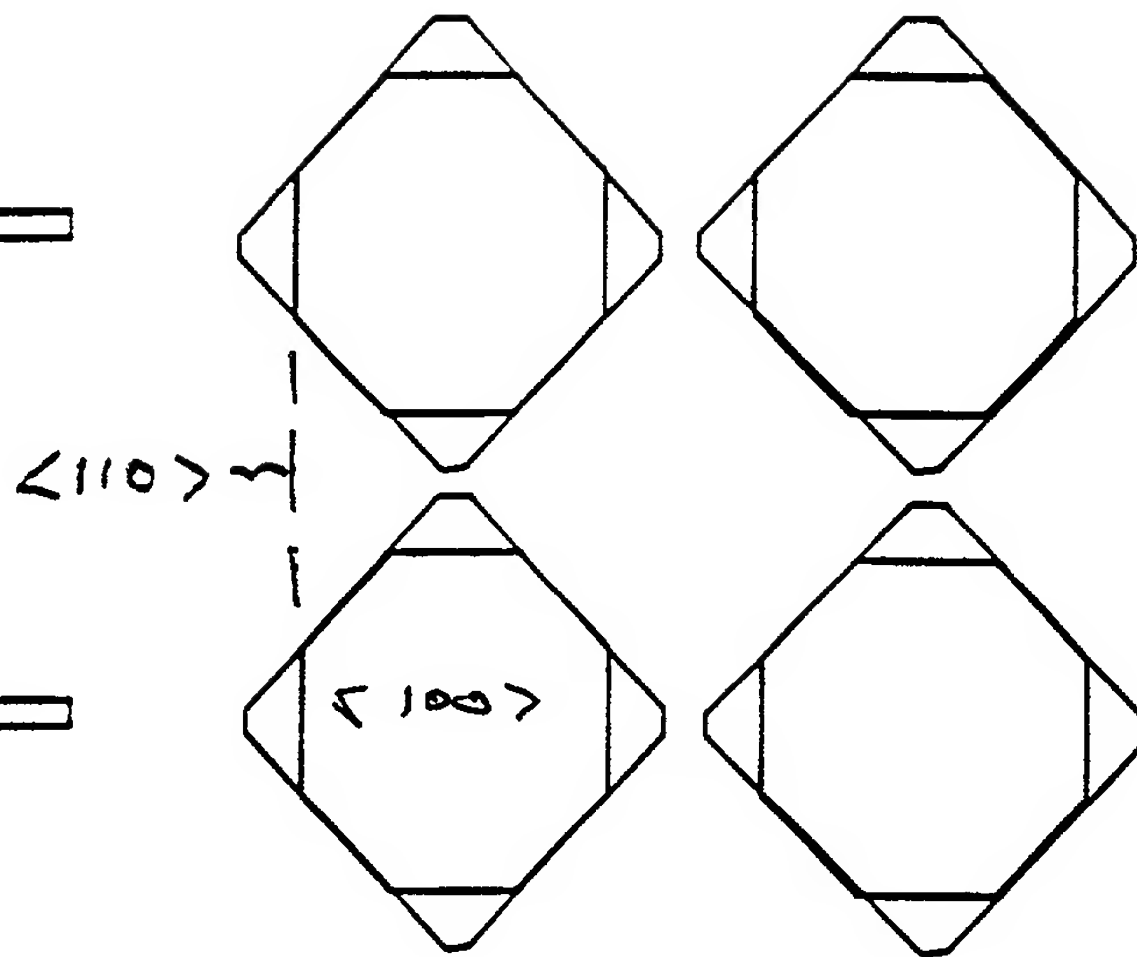


FIG. 1B

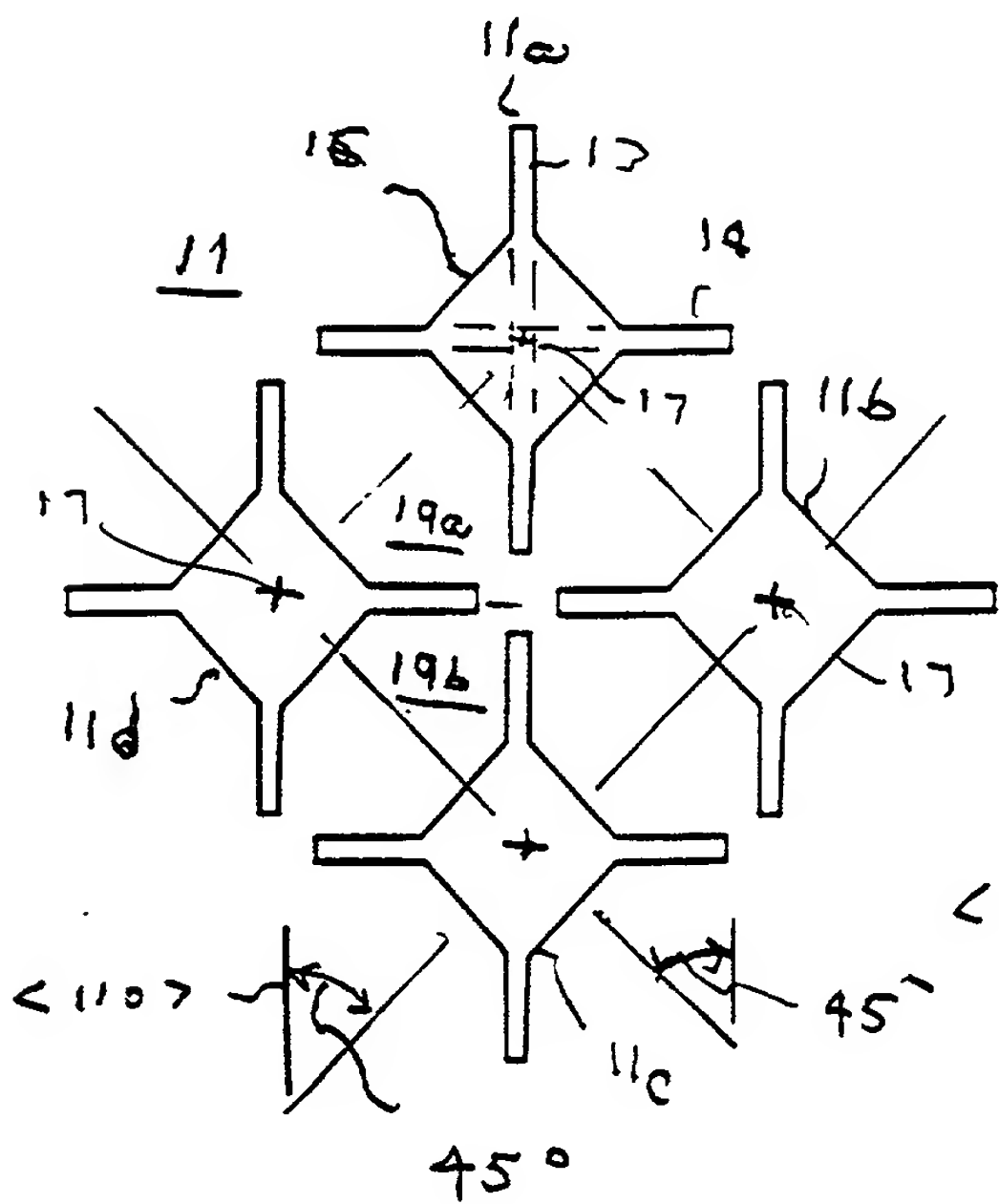


FIG. 2A

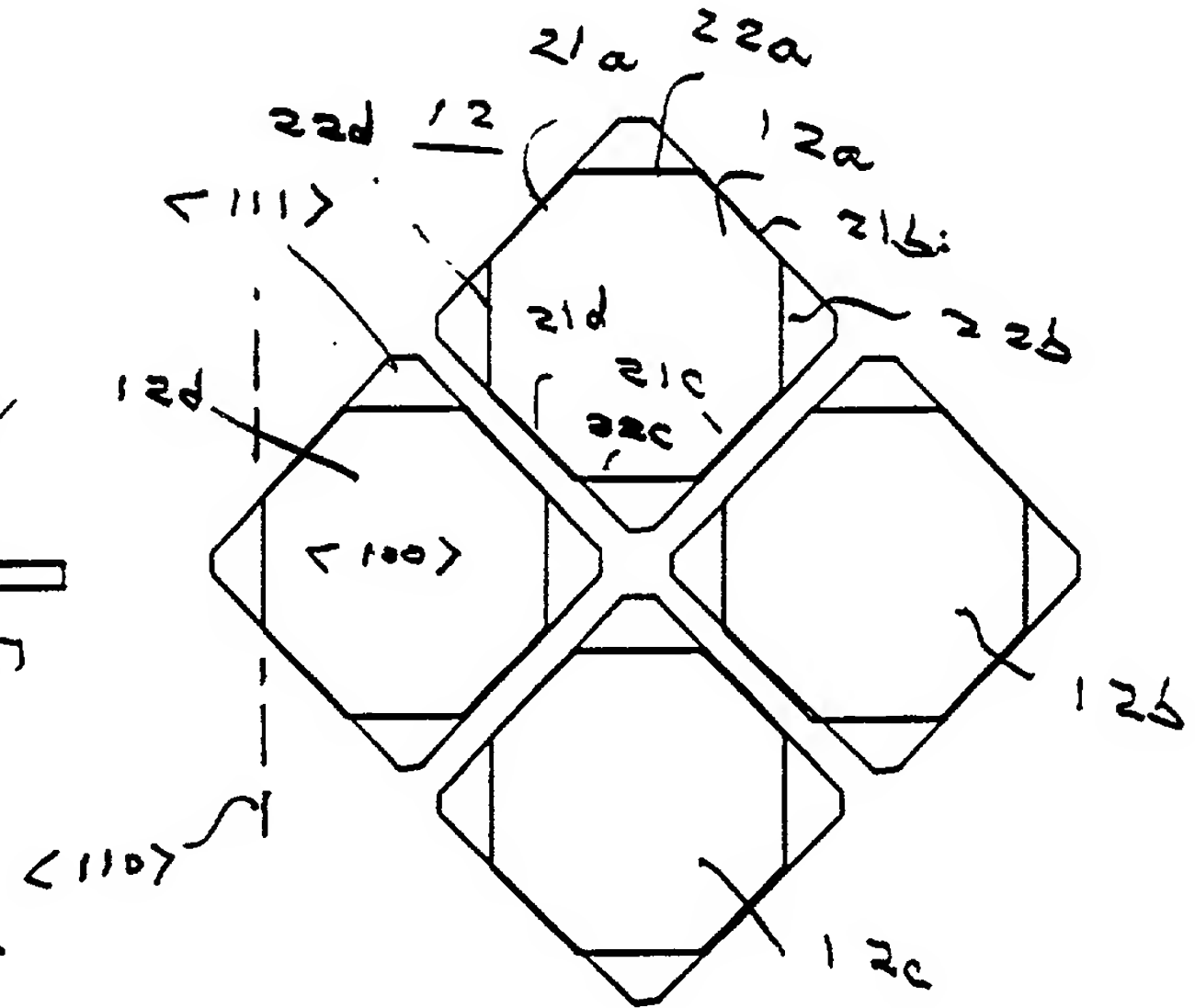


FIG. 2B

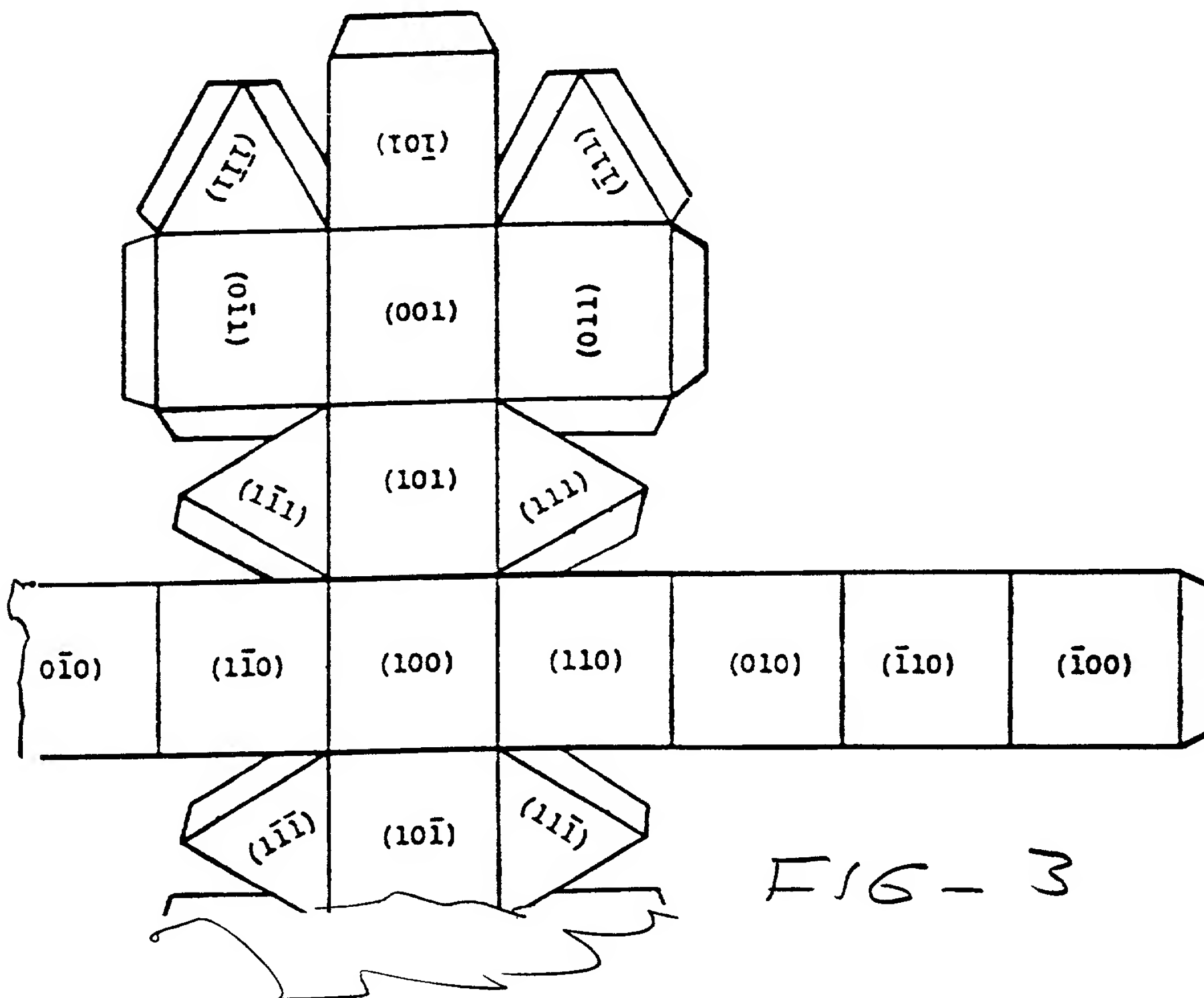


FIG-3

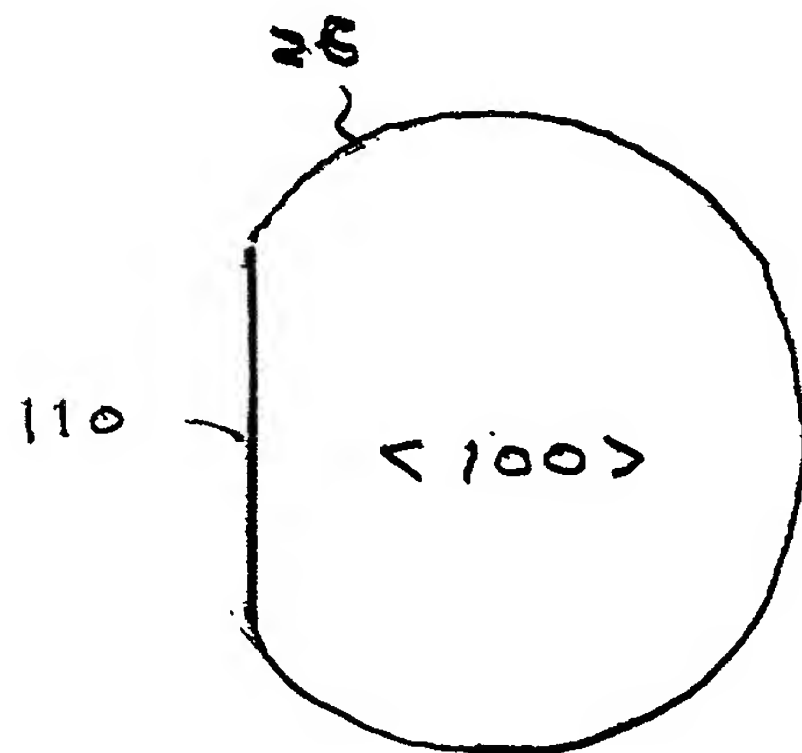
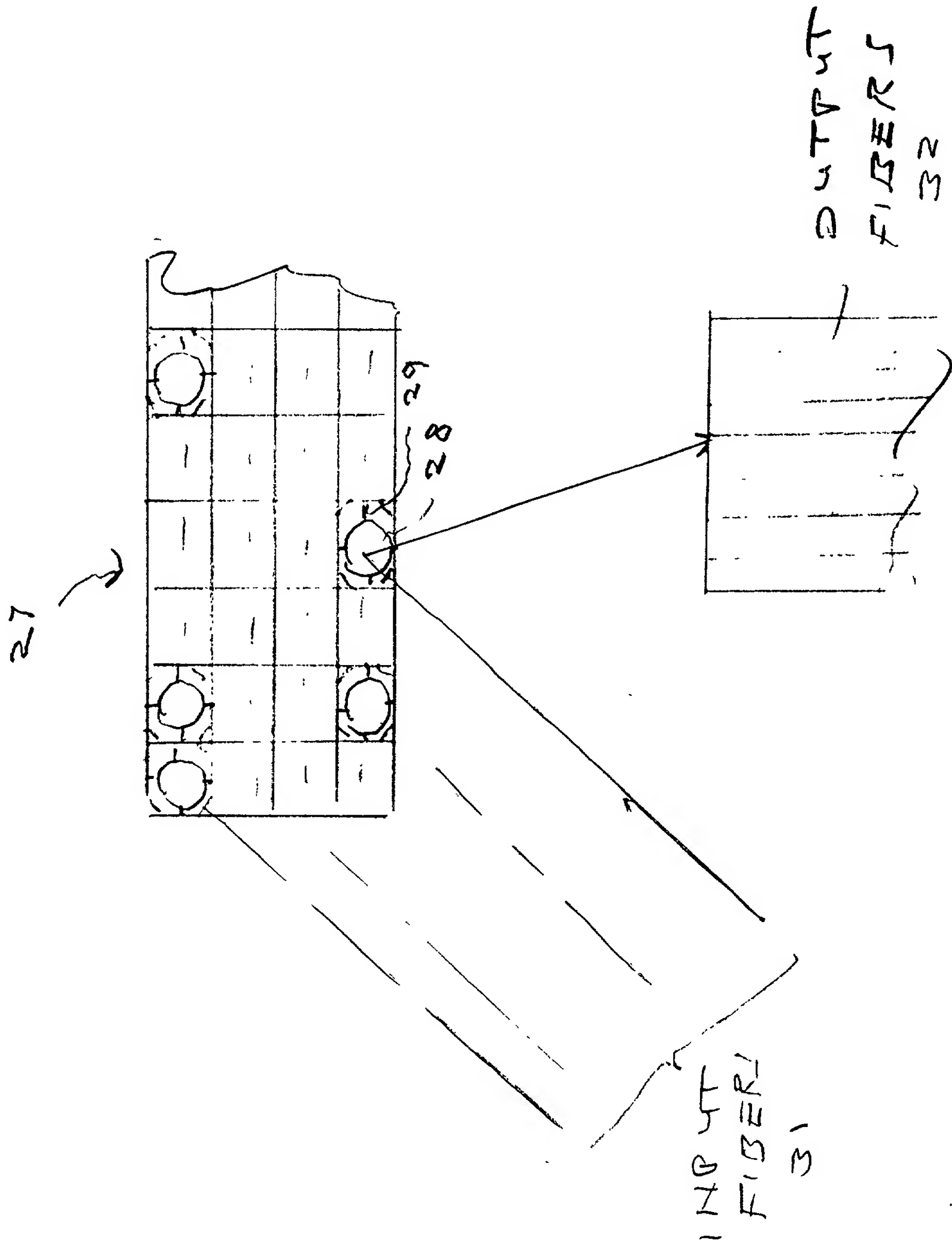


FIG-4



F16-5

- 33 - Providing a semiconductor crystal substrate with a $\langle 100 \rangle$ surface relatively horizontal for placement of a mask and having an alignment feature on the perpendicular $\langle 110 \rangle$ crystal plane
- 34 - Providing a mask with cross arms and a centered diamond with the diamond centers lying on a line offset from the $\langle 110 \rangle$ plane by 45 degrees when the mask is placed in the etching position
- 35 - Doing a KOH etch to provide an array of membranes each being defined by an octagon with four of the sides being a vertical etch back in the $\langle 100 \rangle$ plane and the alternating other four sides being defined by a $\langle 100 \rangle$ axis seeking etch
- 36 - Etching suspended circular and steerable mirrors in each octagon membrane to provide an N by N optical switch

FIG. 6